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**(54) CAPACITANCE TYPE PRESSURE SENSOR AND  
MANUFACTURE THEREOF**

(57) Abstract:

**PROBLEM TO BE SOLVED:** To provide a small, stable and inexpensive capacitance type pressure sensor for measuring a relatively high pressure, and a manufacturing method thereof.

**SOLUTION:** The capacitance type pressure sensor is provided with a diaphragm body 2 having a substrate electrode 24 and a diaphragm part 26, and a seal cap body 3 having a detection electrode 31 wherein the diaphragm body 2 comprises an SOI laminate 21. The SOI laminate 21 has a three layer structure of an outer silicon layer 22, an intermediate silicon oxide layer 23 and an inner low resistance silicon layer 24.

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